Electronic Supplementary Information

Fabrication of Single Phase CsPbBr₃ Films via In-situ Metal Reaction

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Fig. S1.(a), (b) and (c) indicate the sputtering of 20 nm Pb, 40 nm Pb and 60 nm Pb layers on ITO respectively (the true thickness is about ~ 21.05 nm, ~ 44.48 nm, ~ 64.10 nm respectively).



Fig.S2.,Surface SEM images (a) (b) and cross section SEM images (c) (d) of FTO / SnO_2 and FTO / SnO_2 / Pb substrate, respectively.



Fig. S3 The energy level diagram of FTO / SnO_2 /CsPbBr₃ / P3HT / Carbon PSCs. The results show that the energy levels of each structure match.



Fig. S4 The reproducibility of V_{oc} , J_{sc} , FF and PCE parameter values of diverse Pb thickness. The error bar represents the standard deviation from at least 15 experimental trials.